

Substitute Form PTO-1449

U.S. Department of Commerce
Patent and Trademark OfficeAttorney's Docket No.
07977-052001Application No.
08/690,747**Information Disclosure Statement
by Applicant**

(Use several sheets if necessary)

(37 CFR §1.98(b))

Applicant
Hisashi Ohtani et alFiling Date
August 1, 1996Group Art Unit
1765**U.S. Patent Documents**

Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
<i>J</i>	AA	5,956,579	09/21/99	Yamazaki et al.			
<i>K</i>	AB	6,072,193	06/06/00	Ohnuma et al.			
<i>P</i>	AC	6,066,518	05/23/00	Yamazaki			
<i>T</i>	AD	5,244,819	09/14/93	Yue			
<i>U</i>	AE	4,371,403	02/01/83	Ikubo et al.			
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

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Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
<i>J</i>	AL	5-109737	April 30, 1993	Japan			X	
	AM							
	AN							
	AO							
	AP							

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
<i>J</i>	AQ	A. Ourmazd, "Gettering of Impurities in Silicon," Materials Research Society, Vol. 59, 1986, pp.331-340.
<i>T</i>	AR	A. Ourmazd, et al., "Gettering of Metallic Impurities in Silicon," Materials Research Society, Vol. 36, 1985, pp. 25-30.
<i>J</i>	AS	Etienne G. Colas, et al., "Quantitative Study of Metal Gettering in Silicon," Materials Research Society, Vol. 59, 1986, pp. 341-346.
<i>J</i>	AT	K. Graff et al., "Palladium Test: A Tool to Evaluate Gettering Efficiency," Materials Research Society, Vol. 36, 1985, pp. 19-24.

Examiner Signature

Date Considered

EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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